

Stephen Y Chou

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142
papers

15,604
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58
h-index

124
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158
ext. papers

16,823
ext. citations

6
avg, IF

6.41
L-index

#	Paper	IF	Citations
142	Imprint of sub-25 nm vias and trenches in polymers. <i>Applied Physics Letters</i> , 1995 , 67, 3114-3116	3.4	2235
141	Nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1996 , 14, 4129		1393
140	Sub-10 nm imprint lithography and applications. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1997 , 15, 2897		914
139	Fabrication of 5nm linewidth and 14nm pitch features by nanoimprint lithography. <i>Applied Physics Letters</i> , 2004 , 84, 5299-5301	3.4	505
138	Deterministic hydrodynamics: taking blood apart. <i>Proceedings of the National Academy of Sciences of the United States of America</i> , 2006 , 103, 14779-84	11.5	461
137	Statics and dynamics of single DNA molecules confined in nanochannels. <i>Physical Review Letters</i> , 2005 , 94, 196101	7.4	451
136	Ultrafast and direct imprint of nanostructures in silicon. <i>Nature</i> , 2002 , 417, 835-7	50.4	363
135	Single-domain magnetic pillar array of 35 nm diameter and 65 Gbits/in.2 density for ultrahigh density quantum magnetic storage. <i>Journal of Applied Physics</i> , 1994 , 76, 6673-6675	2.5	331
134	A Silicon Single-Electron Transistor Memory Operating at Room Temperature. <i>Science</i> , 1997 , 275, 649-5133.3	33.3	315
133	Imprint lithography with sub-10 nm feature size and high throughput. <i>Microelectronic Engineering</i> , 1997 , 35, 237-240	2.5	303
132	Graphene Transistors Fabricated via Transfer-Printing In Device Active-Areas on Large Wafer. <i>Nano Letters</i> , 2007 , 7, 3840-3844	11.5	293
131	Fabrication of 10 nm enclosed nanofluidic channels. <i>Applied Physics Letters</i> , 2002 , 81, 174-176	3.4	286
130	Silicon single-electron quantum-dot transistor switch operating at room temperature. <i>Applied Physics Letters</i> , 1998 , 72, 1205-1207	3.4	266
129	Micro- and nanofluidics for DNA analysis. <i>Analytical and Bioanalytical Chemistry</i> , 2004 , 378, 1678-92	4.4	256
128	Roller nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1998 , 16, 3926		244
127	Fabrication of 70 nm channel length polymer organic thin-film transistors using nanoimprint lithography. <i>Applied Physics Letters</i> , 2002 , 81, 4431-4433	3.4	234
126	Nanolithographically defined magnetic structures and quantum magnetic disk (invited). <i>Journal of Applied Physics</i> , 1996 , 79, 6101	2.5	227

125	Lithographically induced self-assembly of periodic polymer micropillar arrays. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1999 , 17, 3197		225
124	Observation of quantum effects and Coulomb blockade in silicon quantum-dot transistors at temperatures over 100 K. <i>Applied Physics Letters</i> , 1995 , 67, 938-940	3-4	203
123	Fabrication of large area subwavelength antireflection structures on Si using trilayer resist nanoimprint lithography and liftoff. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2003 , 21, 2874		198
122	Lithographically induced self-construction of polymer microstructures for resistless patterning. <i>Applied Physics Letters</i> , 1999 , 75, 1004-1006	3-4	186
121	Gradient nanostructures for interfacing microfluidics and nanofluidics. <i>Applied Physics Letters</i> , 2002 , 81, 3058-3060	3-4	176
120	Wafer-scale patterning of sub-40 nm diameter and high aspect ratio (>50:1) silicon pillar arrays by nanoimprint and etching. <i>Nanotechnology</i> , 2008 , 19, 345301	3-4	172
119	Nanogap detector inside nanofluidic channel for fast real-time label-free DNA analysis. <i>Nano Letters</i> , 2008 , 8, 1472-6	11.5	170
118	Large area high density quantized magnetic disks fabricated using nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1998 , 16, 3825		162
117	Nano-compact disks with 400 Gbit/in ² storage density fabricated using nanoimprint lithography and read with proximal probe. <i>Applied Physics Letters</i> , 1997 , 71, 3174-3176	3-4	158
116	Three-dimensional cavity nanoantenna coupled plasmonic nanodots for ultrahigh and uniform surface-enhanced Raman scattering over large area. <i>Optics Express</i> , 2011 , 19, 3925-36	3-3	142
115	Large enhancement of upconversion luminescence of NaYF ₄ :Yb ³⁺ /Er ³⁺ nanocrystal by 3D plasmonic nano-antennas. <i>Advanced Materials</i> , 2012 , 24, OP236-41	24	129
114	6 nm half-pitch lines and 0.04 μm ² static random access memory patterns by nanoimprint lithography. <i>Nanotechnology</i> , 2005 , 16, 1058-1061	3-4	128
113	Fabrication of circular optical structures with a 20 nm minimum feature size using nanoimprint lithography. <i>Applied Physics Letters</i> , 2000 , 76, 673-675	3-4	124
112	Single hole quantum dot transistors in silicon. <i>Applied Physics Letters</i> , 1995 , 67, 2338-2340	3-4	117
111	Enhancement of immunoassay's fluorescence and detection sensitivity using three-dimensional plasmonic nano-antenna-dots array. <i>Analytical Chemistry</i> , 2012 , 84, 4489-95	7.8	116
110	Nanoscale silicon field effect transistors fabricated using imprint lithography. <i>Applied Physics Letters</i> , 1997 , 71, 1881-1883	3-4	114
109	A room-temperature silicon single-electron metal oxide semiconductor memory with nanoscale floating-gate and ultranarrow channel. <i>Applied Physics Letters</i> , 1997 , 70, 850-852	3-4	112
108	Single sub-20 nm wide, centimeter-long nanofluidic channel fabricated by novel nanoimprint mold fabrication and direct imprinting. <i>Nano Letters</i> , 2007 , 7, 3774-80	11.5	107

107	Reflective polarizer based on a stacked double-layer subwavelength metal grating structure fabricated using nanoimprint lithography. <i>Applied Physics Letters</i> , 2000 , 77, 927	3.4	104
106	Direct nanoimprint of submicron organic light-emitting structures. <i>Applied Physics Letters</i> , 1999 , 75, 2767-2769	3.4	101
105	Sub-20-nm alignment in nanoimprint lithography using Moiré Fringe. <i>Nano Letters</i> , 2006 , 6, 2626-9	11.5	100
104	Direct three-dimensional patterning using nanoimprint lithography. <i>Applied Physics Letters</i> , 2001 , 78, 3322-3324	3.4	100
103	Fabrication of 60-nm transistors on 4-in. wafer using nanoimprint at all lithography levels. <i>Applied Physics Letters</i> , 2003 , 83, 1632-1634	3.4	99
102	Ultrathin, high-efficiency, broad-band, omni-acceptance, organic solar cells enhanced by plasmonic cavity with subwavelength hole array. <i>Optics Express</i> , 2013 , 21 Suppl 1, A60-76	3.3	97
101	Sacrificial polymers for nanofluidic channels in biological applications. <i>Nanotechnology</i> , 2003 , 14, 578-583	3.4	95
100	Crossing microfluidic streamlines to lyse, label and wash cells. <i>Lab on A Chip</i> , 2008 , 8, 1448-53	7.2	92
99	Nanoimprint Lithography and Lithographically Induced Self-Assembly. <i>MRS Bulletin</i> , 2001 , 26, 512-517	3.2	90
98	Study of nanoscale magnetic structures fabricated using electron-beam lithography and quantum magnetic disk. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1994 , 12, 3695		90
97	Size effects on switching field of isolated and interactive arrays of nanoscale single-domain Ni bars fabricated using electron-beam nanolithography. <i>Journal of Applied Physics</i> , 1994 , 76, 6679-6681	2.5	82
96	Air cushion press for excellent uniformity, high yield, and fast nanoimprint across a 100 mm field. <i>Nano Letters</i> , 2006 , 6, 2438-41	11.5	80
95	Sub-10 nm self-enclosed self-limited nanofluidic channel arrays. <i>Nano Letters</i> , 2008 , 8, 3830-3	11.5	79
94	Hydrodynamic metamaterials: microfabricated arrays to steer, refract, and focus streams of biomaterials. <i>Proceedings of the National Academy of Sciences of the United States of America</i> , 2008 , 105, 7434-8	11.5	75
93	Multilayer resist methods for nanoimprint lithography on nonflat surfaces. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1998 , 16, 3922		73
92	Large area direct nanoimprinting of SiO ₂ /TiO ₂ gel gratings for optical applications. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2003 , 21, 660		72
91	Giant and uniform fluorescence enhancement over large areas using plasmonic nanodots in 3D resonant cavity nanoantenna by nanoimprinting. <i>Nanotechnology</i> , 2012 , 23, 225301	3.4	71
90	Observation of dynamic behavior of lithographically induced self-assembly of supramolecular periodic pillar arrays in a homopolymer film. <i>Applied Physics Letters</i> , 2001 , 79, 1688-1690	3.4	70

89	Fabrication of a new broadband waveguide polarizer with a double-layer 190 nm period metal-gratings using nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1999 , 17, 2957		70
88	Multilevel nanoimprint lithography with submicron alignment over 4 in. Si wafers. <i>Applied Physics Letters</i> , 2001 , 79, 845-847	3.4	67
87	Air bubble formation and dissolution in dispensing nanoimprint lithography. <i>Nanotechnology</i> , 2007 , 18, 025303	3.4	66
86	Improved nanofabrication through guided transient liquefaction. <i>Nature Nanotechnology</i> , 2008 , 3, 295-300.	3.7	63
85	Fabrication of large area 100 nm pitch grating by spatial frequency doubling and nanoimprint lithography for subwavelength optical applications. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2001 , 19, 2816		59
84	Quantification of magnetic force microscopy using a micronscale current ring. <i>Applied Physics Letters</i> , 1997 , 70, 2043-2045	3.4	58
83	Ultrafast patterning of nanostructures in polymers using laser assisted nanoimprint lithography. <i>Applied Physics Letters</i> , 2003 , 83, 4417-4419	3.4	57
82	Extraordinary light transmission through opaque thin metal film with subwavelength holes blocked by metal disks. <i>Optics Express</i> , 2011 , 19, 21098-108	3.3	52
81	Fabrication of nanoscale gratings with reduced line edge roughness using nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2003 , 21, 2089		52
80	Controlling polarization of vertical-cavity surface-emitting lasers using amorphous silicon subwavelength transmission gratings. <i>Applied Physics Letters</i> , 1996 , 69, 7-9	3.4	48
79	Fabrication of single-domain magnetic pillar array of 35 nm diameter and 65 Gbits/in.2 density. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1994 , 12, 3639		48
78	Dynamic modeling and scaling of nanostructure formation in the lithographically induced self-assembly and self-construction. <i>Applied Physics Letters</i> , 2003 , 82, 3200-3202	3.4	46
77	Plasmonic Nanocavity Organic Light-Emitting Diode with Significantly Enhanced Light Extraction, Contrast, Viewing Angle, Brightness, and Low-Glare. <i>Advanced Functional Materials</i> , 2014 , 24, 6329-6339	15.6	45
76	Self-formation of sub-60-nm half-pitch gratings with large areas through fracturing. <i>Nature Nanotechnology</i> , 2007 , 2, 545-8	28.7	45
75	Electrohydrodynamic instability of a thin film of viscoelastic polymer underneath a lithographically manufactured mask. <i>Journal of Non-Newtonian Fluid Mechanics</i> , 2005 , 125, 91-99	2.7	45
74	Ultrahigh resolution magnetic force microscope tip fabricated using electron beam lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1993 , 11, 2570		45
73	Ultrasensitive Ebola Virus Antigen Sensing via 3D Nanoantenna Arrays. <i>Advanced Materials</i> , 2019 , 31, e1902331	24	44
72	Electrostatic force-assisted nanoimprint lithography (EFAN). <i>Nano Letters</i> , 2005 , 5, 527-30	11.5	44

71	10 nm Si pillars fabricated using electron-beam lithography, reactive ion etching, and HF etching. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1993 , 11, 2524		44
70	100 nm period gratings produced by lithographically induced self-construction. <i>Nanotechnology</i> , 2003 , 14, 786-790	3.4	42
69	Triangular Profile Imprint Molds in Nanograting Fabrication. <i>Nano Letters</i> , 2004 , 4, 341-344	11.5	42
68	Fabrication of planar quantum magnetic disk structure using electron beam lithography, reactive ion etching, and chemical mechanical polishing. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1995 , 13, 2850		42
67	Pattern transfer fidelity of nanoimprint lithography on six-inch wafers. <i>Nanotechnology</i> , 2003 , 14, 33-36	3.4	39
66	Perpendicular quantized magnetic disks with 45 Gbits on a 4 μ m ² area. <i>Journal of Applied Physics</i> , 1999 , 85, 5534-5536	2.5	39
65	Fabrication and characterization of room temperature silicon single electron memory. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1997 , 15, 2840		37
64	Tunable Liquid Crystal-Resonant Grating Filter Fabricated by Nanoimprint Lithography. <i>IEEE Photonics Technology Letters</i> , 2007 , 19, 1457-1459	2.2	35
63	In situ real time process characterization in nanoimprint lithography using time-resolved diffractive scatterometry. <i>Applied Physics Letters</i> , 2004 , 85, 4166-4168	3.4	35
62	Subwavelength amorphous silicon transmission gratings and applications in polarizers and waveplates. <i>Applied Physics Letters</i> , 1995 , 67, 742-744	3.4	34
61	Fabrication of a Molecular Self-Assembled Monolayer Diode Using Nanoimprint Lithography. <i>Nano Letters</i> , 2003 , 3, 1687-1690	11.5	33
60	Room-temperature Si single-electron memory fabricated by nanoimprint lithography. <i>Applied Physics Letters</i> , 2003 , 83, 2268-2270	3.4	32
59	Cylindrically symmetric electrohydrodynamic patterning. <i>Physical Review E</i> , 2004 , 70, 041601	2.4	30
58	Fabrication of nanocontacts for molecular devices using nanoimprint lithography. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2002 , 20, 665		30
57	High-modulation-depth and short-cavity-length silicon Fabry-Berot modulator with two grating Bragg reflectors. <i>Applied Physics Letters</i> , 1996 , 68, 170-172	3.4	28
56	Study of magnetic properties of magnetic force microscopy probes using micronscale current rings. <i>Journal of Applied Physics</i> , 1997 , 81, 5026-5028	2.5	26
55	Effects of bar length on switching field of nanoscale nickel and cobalt bars fabricated using lithography. <i>Journal of Applied Physics</i> , 1996 , 80, 5205-5208	2.5	26
54	Plasmonic bar-coupled dots-on-pillar cavity antenna with dual resonances for infrared absorption and sensing: performance and nanoimprint fabrication. <i>ACS Nano</i> , 2014 , 8, 2618-24	16.7	25

53	The fabrication of periodic metal nanodot arrays through pulsed laser melting induced fragmentation of metal nanogratings. <i>Nanotechnology</i> , 2009 , 20, 285310	3.4	25
52	High-efficiency and high-speed silicon metal-semiconductor-metal photodetectors operating in the infrared. <i>Applied Physics Letters</i> , 1997 , 70, 753-755	3.4	25
51	Sub-10-nm wide trench, line, and hole fabrication using pressed self-perfection. <i>Nano Letters</i> , 2008 , 8, 1986-90	11.5	25
50	Lithographically induced self-assembly of microstructures with a liquid-filled gap between the mask and polymer surface. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2001 , 19, 2741		23
49	Quantum magnetic disk. <i>Journal of Magnetism and Magnetic Materials</i> , 1996 , 155, 151-153	2.8	23
48	Large area 50nm period grating by multiple nanoimprint lithography and spatial frequency doubling. <i>Applied Physics Letters</i> , 2007 , 90, 043118	3.4	22
47	Molecular alignment in submicron patterned polymer matrix using nanoimprint lithography. <i>Applied Physics Letters</i> , 2000 , 77, 166-168	3.4	22
46	Single-electron Coulomb blockade in a nanometer field-effect transistor with a single barrier. <i>Applied Physics Letters</i> , 1992 , 61, 1591-1593	3.4	20
45	Enhancement and electric charge-assisted tuning of nonlinear light generation in bipolar plasmonics. <i>Nano Letters</i> , 2014 , 14, 2822-30	11.5	19
44	Ultrafast direct imprinting of nanostructures in metals by pulsed laser melting. <i>Nanotechnology</i> , 2010 , 21, 045303	3.4	19
43	Internal emission metal-semiconductor-metal photodetectors on Si and GaAs for 1.3 μ m detection. <i>Applied Physics Letters</i> , 1995 , 66, 2673-2675	3.4	19
42	Single electron and hole quantum dot transistors operating above 110 K. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1995 , 13, 2865		19
41	Printing of sub-20 nm wide graphene ribbon arrays using nanoimprinted graphite stamps and electrostatic force assisted bonding. <i>Nanotechnology</i> , 2011 , 22, 445301	3.4	18
40	Applications of excimer laser in nanofabrication. <i>Applied Physics A: Materials Science and Processing</i> , 2010 , 98, 9-59	2.6	18
39	Fabrication and performance of thin amorphous Si subwavelength transmission grating for controlling vertical cavity surface emitting laser polarization. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1996 , 14, 4055		18
38	Tunable External Cavity Laser With a Liquid-Crystal Subwavelength Resonant Grating Filter as Wavelength-Selective Mirror. <i>IEEE Photonics Technology Letters</i> , 2007 , 19, 1099-1101	2.2	17
37	Nanoimprint mold fabrication and replication by room-temperature conformal chemical vapor deposition. <i>Applied Physics Letters</i> , 2007 , 90, 203115	3.4	17
36	Ultrafast and selective reduction of sidewall roughness in silicon waveguides using self-perfection by liquefaction. <i>Nanotechnology</i> , 2009 , 20, 345302	3.4	16

35	Effect of bar width on magnetoresistance of nanoscale nickel and cobalt bars. <i>Journal of Applied Physics</i> , 1997 , 81, 5461-5463	2.5	16
34	Double 15-nm-wide metal gates 10 nm apart and 70 nm thick on GaAs. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1990 , 8, 1919		16
33	Fabrication of sub-50 nm finger spacing and width high-speed metal-semiconductor-metal photodetectors using high-resolution electron beam lithography and molecular beam epitaxy. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1991 , 9, 2920		15
32	Fabrication of a 60-nm-diameter perfectly round metal-dot array over a large area on a plastic substrate using nanoimprint lithography and self-perfection by liquefaction. <i>Small</i> , 2010 , 6, 1242-7	11	14
31	Fabrication of sub-25 nm diameter pillar nanoimprint molds with smooth sidewalls using self-perfection by liquefaction and reactive ion etching. <i>Nanotechnology</i> , 2008 , 19, 455301	3-4	14
30	32 GHz metal-semiconductor-metal photodetectors on crystalline silicon. <i>Applied Physics Letters</i> , 1992 , 61, 1760-1762	3-4	13
29	Growth of straight silicon nanowires on amorphous substrates with uniform diameter, length, orientation, and location using nanopatterned host-mediated catalyst. <i>Nano Letters</i> , 2011 , 11, 5247-51	11.5	12
28	Self-aligned fabrication of 10 nm wide asymmetric trenches for Si/SiGe heterojunction tunneling field effect transistors using nanoimprint lithography, shadow evaporation, and etching. <i>Journal of Vacuum Science & Technology B</i> , 2009 , 27, 2790		12
27	Polarimetry of thin metal transmission gratings in the resonance region and its impact on the response of metal-semiconductor-metal photodetectors. <i>Applied Physics Letters</i> , 1997 , 70, 2673-2675	3-4	12
26	Silicon nanopillar anodes for lithium-ion batteries using nanoimprint lithography with flexible molds. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2014 , 32, 06FG10	1.3	11
25	Alkylsiloxane self-assembled monolayer formation guided by nanoimprinted Si and SiO ₂ templates. <i>Applied Physics Letters</i> , 2006 , 89, 153121	3-4	11
24	A novel method for fabricating sub-16 nm footprint T-gate nanoimprint molds. <i>Nanotechnology</i> , 2009 , 20, 185302	3-4	9
23	Fabrication of high aspect ratio metal nanotips by nanosecond pulse laser melting. <i>Nanotechnology</i> , 2008 , 19, 345303	3-4	8
22	Materials Aspects in Micro- and Nanofluidic Systems Applied to Biology. <i>MRS Bulletin</i> , 2006 , 31, 108-113	3.2	8
21	In situ real time monitoring of nanosecond imprint process. <i>Applied Physics Letters</i> , 2006 , 89, 073107	3-4	8
20	Current fluctuations in double-barrier quantum well resonant tunneling diodes. <i>Applied Physics Letters</i> , 1991 , 59, 1105-1107	3-4	8
19	Self-limited self-perfection by liquefaction for sub-20 nm trench/line fabrication. <i>Nanotechnology</i> , 2009 , 20, 465305	3-4	7
18	Application of amorphous silicon subwavelength gratings in polarization switching vertical-cavity surface-emitting lasers. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1997 , 15, 2864		7

17	Filling of nano-via holes by laser-assisted direct imprint. <i>Microelectronic Engineering</i> , 2006 , 83, 1547-1550.	2.5	7
16	Response to Comment on Fabrication of a Molecular Self-Assembled Monolayer Diode Using Nanoimprint Lithography' <i>Nano Letters</i> , 2004 , 4, 535-535	11.5	7
15	Integration of Metallic Nanostructures in Fluidic Channels for Fluorescence and Raman Enhancement by Nanoimprint Lithography and Lift-off on Compositional Resist Stack. <i>Microelectronic Engineering</i> , 2012 , 98, 693-697	2.5	6
14	RIMS (real-time imprint monitoring by scattering of light) study of pressure, temperature and resist effects on nanoimprint lithography. <i>Nanotechnology</i> , 2007 , 18, 065304	3.4	6
13	Nanolithographically defined magnetic structures. <i>Scripta Metallurgica Et Materialia</i> , 1995 , 33, 1537-1544		6
12	The anti-lotus leaf effect in nanohydrodynamic bump arrays. <i>New Journal of Physics</i> , 2010 , 12, 085008	2.9	5
11	Effects of sample size and field orientation on pseudo-Hall voltage in micronscale nickel thin-film squares. <i>Journal of Applied Physics</i> , 1997 , 81, 5475-5477	2.5	5
10	Quantized patterning using nanoimprinted blanks. <i>Nanotechnology</i> , 2009 , 20, 155303	3.4	3
9	Nanoimprint Lithography. <i>Nanostructure Science and Technology</i> , 2003 , 15-23	0.9	3
8	Fabrication and properties of visible-light subwavelength amorphous silicon transmission gratings. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 1995 , 13, 2879		2
7	2014 ,		1
6	Electric Current Tuning the Self-Oscillation Frequency of EC-VCSELS. <i>IEEE Photonics Technology Letters</i> , 2013 , 25, 1707-1710	2.2	1
5	Drive-Current Tuning of Self-Oscillation Frequency of External Cavity VCSEL 2011 ,		1
4	Nanoscale negative-tone quantized patterning by novel selective electrochemical etching of a nanoimprinted sub-200 nm bimetallic tile array. <i>Nanotechnology</i> , 2012 , 23, 355303	3.4	1
3	Nanoimprint (Technology, Tools, Applications and Commercialization) And New Technologies Beyond 2007 ,		1
2	Group velocities in coplanar strip transmission lines on Si and Si/SiO ₂ /Si substrates measured using differential electro-optic sampling. <i>Applied Physics Letters</i> , 1996 , 69, 2861-2863	3.4	1
1	Nonmonotonic length dependence of switching field of nanolithographically defined single-domain nickel and cobalt bars (abstract). <i>Journal of Applied Physics</i> , 1996 , 79, 5067	2.5	1